



Substitute for Form 1449/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Complete if Known

Application Number	10/082,397
Filing Date	August 6, 2002
First Named Inventor:	Mark W. Miles
Art Unit	2873
Examiner Name	Mai, Huy Kim
Attorney Docket Number	005652.P013XCD

Sheet

1

2

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (If known)				
HM		US-	4,900,395	2/13/90	Syverson et al.	
HM		US-	5,293,272	3/8/94	Jansson et al.	
HM		US-	5,358,601	10/25/94	Cathey	
HM		US-	5,726,480	3/10/98	Pister	
HM		US-	5,793,504	8/11/98	Stoll	
HM		US-	5,808,780	9/15/98	McDonald	
HM		US-	5,943,158	8/24/99	Ford et al.	
HM		US-	6,100,872	8/8/00	Aratani et al.	
HM		US-	6,243,149 B1	6/5/01	Swanson et al.	
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FOREIGN PATENT DOCUMENTS

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		Country Code ³	Number ⁴	Kind Code ⁵ (if known)				

Examiner
Signature

Mai

Date Considered

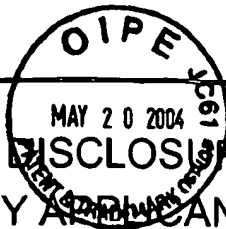
7/12/04

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹Applicant's unique citation designation number (optional). ²See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴For Japanese patent documents, the indication of the year of reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to place a check mark here if English language translation is attached.

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Sheet	2	of	2	Attorney Docket Number		005652.P013XCD
NON PATENT LITERATURE DOCUMENTS						
Examiner Initials*	Cite No ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published				T ²
hm		IBBOTSON, et al. "Comparison of XeF ₂ and F-atom reactions with Si and SiO ₂ ", Applied Physics Letters. Vol. 44, No. 12, June 1984. pp 1129-1131.				
hm		SCHNAKENBERG, et al. "Tmahw Etchants for Silicon Micromachining". 1991 International Conference on Solid State Sensors and Actuators - Digest of Technical Papers. pp. 815-818.				
hm		WILLIAMS, et al. "Etch Rates for Micromachining Processing", Journal of Microelectromechanical Systems. Vol. 5 No. 4, December 1996, pp 256-269.				
hm		WINTERS, et al., "The etching of silicon with XeF ₂ vapor". Applied Physics Letters, Vol. 34. No. 1, Jan. 1979, pp. 70-73.				

Examiner Signature	Mai	Date Considered	7/12/04
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